

Resists for Nanoimprint Lithography



Ready-to-use Formulations from the Industrial Pioneer of Nanoimprint Lithography (NIL) Materials

- Excellent film quality
- High replication fidelity
- Extra dry etching performance
- Superior working stamp compatibility
- Customized and tailored solutions available
- Safe solvents specified for industrial requirements
- Manufacturing according to ISO 9001 and ISO 14001

- Made in Germany -

micro resist technology GmbH

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Nanoimprint Lithography

Process description

Nanoimprint Lithography (NIL) is a straight forward, low cost, and high throughput capable technology for the fabrication of nanometer scaled patterns. Main application fields are photonics, next generation electronics, as well as Life Science and sensor applications.

Thermal-NIL, T-NIL

Pros

- Dry polymer thin film with excellent film stability after coating
- No primer required
- Low shrinkage
- Resist still soluble in common solvents after imprinting (most cases)

Cons

- Glass transition temperature (T_g) remains after imprinting (reflow possible)
- Requires temperature ($T_i = T_g + 60K$) and pressure (up to 5 bar)
- Long process cycle times
- CTE misalignment considerable on large area

UV-NIL

Pros

- Fast process cycle times
- Low pressure (< 100 mbar) at room temperature
- Technology of choice for large area and HVM
- Open for alternative coating technologies (solvent-free formulations possible)
- Resist properties can be easily tailored, functional materials available

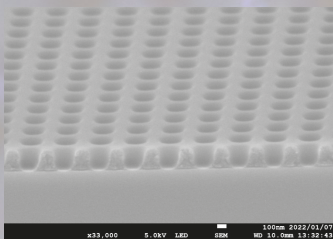
Cons

- Liquid thin film after coating
- Shrinkage during curing needs to be compensated for some applications
- Resist is insoluble in common solvents after imprinting due to cross-linking

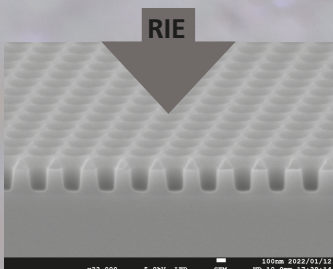
NIL Technological Benefits

- Spatial pattern resolution $< 100nm$
- High throughput, fast processing
- Continuous processing (Roll-to-Roll and Roll-to-Plate available)
- Feasibility almost independent of pattern architecture

→ NIL is the most effective fabrication method of nanostructures



mr-NIL212FC imprint of $\varnothing = 200nm$, $AR = 1$, residual layer thickness $< 10nm$.



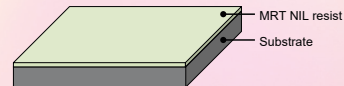
Pattern transfer into SiO_2 , selectivity : 2.25

Thermal Nanoimprint Lithography (T-NIL)

UV-Nanoimprint Lithography (UV-NIL)

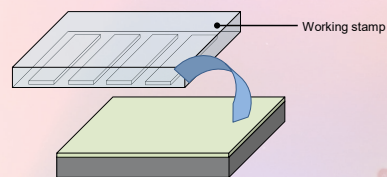
1. Spin-coating of MRT NIL resist and post exposure bake

Solid thin film of thermoplastic polymer

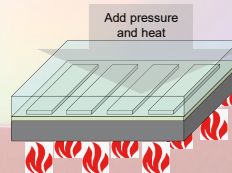


Liquid thin film of photo-reactive NIL resist formulation

2. Align stamp and attach



3. Nanoimprint step



Heat 60K above the glass transition temperature of the T-NIL resist and add some pressure

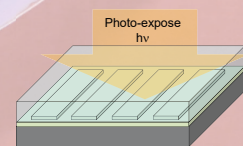
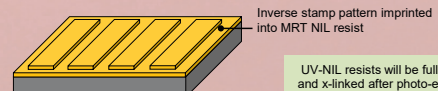


Photo-exposure will start the polymerization of the UV-NIL resist at room temperature

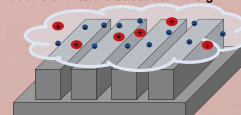
4. Detach stamp

Thermoplastic T-NIL resists will not cure → glass transition temperature still limits further processing under thermal load



UV-NIL resists will be fully cured and x-linked after photo-exposure

5. Pattern transfer into the substrate via e.g. RIE



Nanoimprint Lithography

Resist solutions – Ready to use formulations

micro resist technology GmbH has provided tailor-made resist formulations for nanoimprint lithography (NIL) since 1999. The unique key features of our products are outstanding film forming and imprinting performance beside excellent pattern fidelity and plasma etch stability. Our nanoimprint resists are mostly applied as dry etch masks for pattern transfer into various substrates, like Si, SiO₂, Al or sapphire.

UV-NIL, Photo-NIL

UV+T-NIL

Thermal-NIL, T-NIL

Product series (Chemistry behind)	Material Key Performance Indicators	Standard film thickness*	Tailored film thickness*
mr-NIL210 (Acrylic)	<ul style="list-style-type: none"> Compatible to gas-permeable flexible working stamp materials (e.g. PDMS, PDMS-like and others) Excellent liquid thin film long-term stability and homogeneity Enables minimized residual layer thickness control 	100nm 200nm 500nm	100nm – 38µm
mr-NIL212FC (Acrylic)	<ul style="list-style-type: none"> Compatible to gas-permeable flexible working stamp materials (e.g. PDMS, PDMS-like and others) Compatible to low intensity light sources (< 40 mW cm⁻²) Higher dry etching stability compared to mr-NIL210 (>2 for SiO₂) Enables minimized residual layer thickness control 	100nm 200nm 500nm	100nm – 500nm
mr-NIL200 (Acrylic)	<ul style="list-style-type: none"> Low viscosity: excellent compatibility to gas-impermeable working stamps (e.g. OrmoStamp¹, SiO₂, Ni) No primer or adhesion promoter necessary for many substrate materials Oxygen insensitive curing chemistry 	100nm 200nm 300nm	100nm – 500nm
mr-UVCur26SF (Acrylic)	<ul style="list-style-type: none"> Solvent-free and low viscosity for inkjet dispensing Low autofluorescence and excellent biocompatibility UV/vis transparent with good thermal stability 	Inkjet	700 nm**
mr-NIL 6000E (Epoxy)	<ul style="list-style-type: none"> For combined UV- and T-NIL approaches Fast process cycle times due to isothermal NIL-process Outstanding dry etching stability No primer required Compatible to PDMS-based working stamp materials 	100nm 200nm 300nm	100nm – 3µm
mr-I 9000M (Thermoset)	<ul style="list-style-type: none"> Thermosetting polymer (crosslinking at imprint temperature, isothermal NIL-process) T_g = 35 °C, no T_g after imprinting (stable up to 260°C after imprint) Excellent dry etching stability Optically clear after imprint for permanent applications 	100nm 200nm 300nm	100nm – 1000nm
mr-I 7000R (Thermoplast)	<ul style="list-style-type: none"> Purely organic, stamp release force optimized Higher etching stability over PMMA T_g = 55°C 	100nm 200nm 300nm	100nm – 300nm
mr-I 8000R (Thermoplast)	<ul style="list-style-type: none"> Purely organic, stamp release force optimized Higher etching stability over PMMA T_g = 115°C 	100nm 200nm 300nm	100nm – 300nm
mr-I PMMA35k (Thermoplast)	<ul style="list-style-type: none"> Purely organic T_g = 105°C 	-	-
SIPOL (Thermoplast)	<ul style="list-style-type: none"> Si-containing etch mask for pattern magnification in a bilayer process Perfect match to transfer layer UL1 Excellent flow characteristics for fast filling of stamp cavities 	100nm 200nm	60nm – 200nm
mr-I T85 (Thermoplast)	<ul style="list-style-type: none"> Based on COC (cyclic olefin copolymer) High chemical resistance towards acids, bases and most organic solvents Superior UV/vis transparency Perfect choice for e.g. µ-fluidic and bio applications, lab-on-chip 	100nm 300nm 500nm 1µm	100nm – 20µm

* Specification of the film thickness measurement: spin-coating on 4 inch Silicon wafers @ 3000 rpm for 30 sec. followed by the recommended pre-exposure bake conditions

** Material developed for inkjet dispensing, film thickness is not adjustable by using a thinner

Nanoimprint Lithography

Process subtleties

NIL with hard, rigid, and gas-impermeable stamps

Main application fields

Optics, nanophotonics

Main technology drivers

No pattern collapse even for high aspect ratio nano-structures
No distortion of working stamp
Long stamp lifetime (additional anti-sticking layer required in many cases)

Typical imprint materials

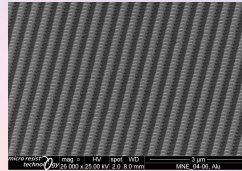
UV-NIL mr-NIL200, mr-UVCur26SF

T-NIL mr-I 7000R/8000R, mr-I 9000M, SIPOL, mr-I T85

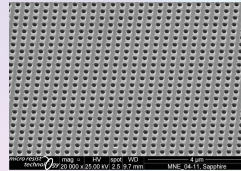
Typical stamp materials

e.g. OrmoStamp^{®1}, SiO₂, glass, Si, Ni, polymers

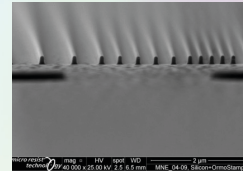
Application examples



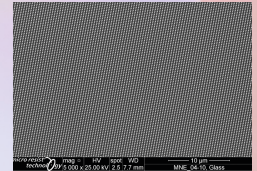
mr-NIL200 pillars on Al (Ø = 200nm, AR 1.5)



mr-NIL200 holes on sapphire (Ø = 200nm, AR 1.5)



mr-NIL200 lines and spaces on Si (width = 75nm, AR3)



mr-NIL200 pillars on glass (Ø = 200nm, AR 1.5)

NIL with soft and gas-permeable stamp materials

Main application fields

Optics, Nanophotonics, functional surfaces

Main technology drivers

Conformal contact also to non-flat substrates
Excellent control of residual layer thickness (RLT)
Working stamp materials with intrinsic anti-sticking properties available^{2,3}

Typical imprint materials

UV-NIL mr-NIL210, mr-NIL212FC

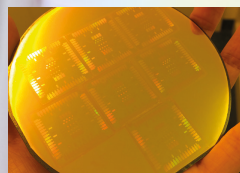
UV- and T-NIL mr-NIL 6000E

T-NIL SIPOL

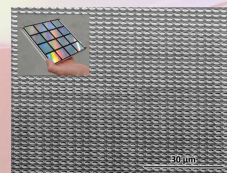
Typical stamp materials

e.g. PDMS-types, KER-4690 UV-PDMS², other polymers³

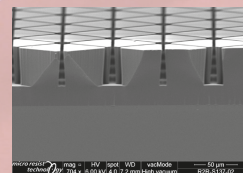
Application examples



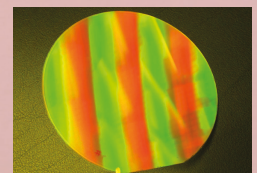
mr-NIL210 on gold coated non-flat polymer film (imprinted with UV-PDMS² stamp, residual layer thickness < 10 nm)



Metal direct etch with mr-NIL210 mask (imprinted with PDMS). Courtesy of smart materials solutions, Inc.



Imprint of undercut structures with mr-NIL210 on Si, applied working stamp UV-PDMS²



mr-NIL212FC pillars on sapphire (Ø = 2µm, imprinted with GMN³ working stamp).

¹ OrmoStamp[®] see separate flyer of MRTs Hybrid Polymers, ² KER-4690 UV-PDMS, from Shin-Etsu, Japan, available from MRT, ³ GMN working stamp series of OpTool ApS, Sweden

Nanoimprint Lithography Solutions

Selected processes for specific applications

NIL and lift-off

Main application fields

Nanophotonics, metamaterials, metasurfaces, nanoparticles manufacturing, nanoelectronics

Main technology drivers

Multiple metal architectures in nanoscale possible (stacks of different metals can be realized)
Good control of lift-off performance by combination with UV-NIL
Excellent control of residual layer thickness possible via slight under-filling of stamp cavities
Single layer lift-off possible with T-NIL on small area

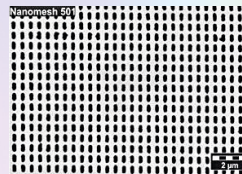
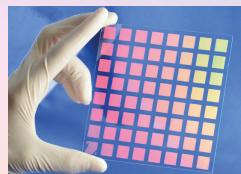
Typical imprint materials

UV-NIL mr-NIL210/LOR, mr-NIL212FC/LOR¹

T-NIL mr-I 7000R, mr-I 8000R

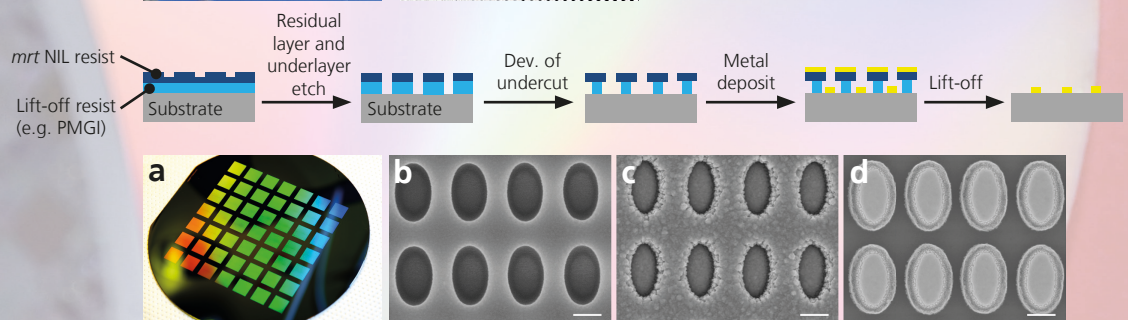
(metal side-wall deposition needs to be considered / avoided)

Application examples



Metal nanomeshes after step-and-repeat imprint with mr-NIL212FC on LOR1, left: photograph 10x10 cm² glass substrate after imprint, right: SEM micrograph of a metal nanomesh after lift-off (holes with 200nm length, 100nm width). Courtesy of Profactor GmbH

Process description



Manufacturing process of metallic nanostructures via imprint of mr-NIL212FC on LOR1A, a) image of the imprinted wafer, SEM micrographs b) after development of the underlayer, c) after metal deposition, d) after lift-off (patterns 200nm length, 100nm width). Courtesy of Profactor GmbH

NIL and deep etching via pattern magnification

Main application fields

Optics, nanophotonics, etching of deep trenches

Main technology drivers

Low aspect ratio imprint → high aspect ratio deep etching

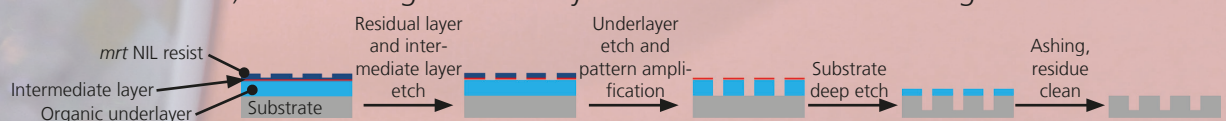
Typical imprint materials

UV-NIL mr-NIL210/SiO₂/UL1², mr-NIL212FC/SiO₂/UL1²

T-NIL SIPOL/UL1²

Process description

1) Pattern magnification by the use of silicon containing NIL resists



2) Pattern magnification by the use of hard mask intermediates (e.g. SiO₂, Cr, Si-containing polymers)

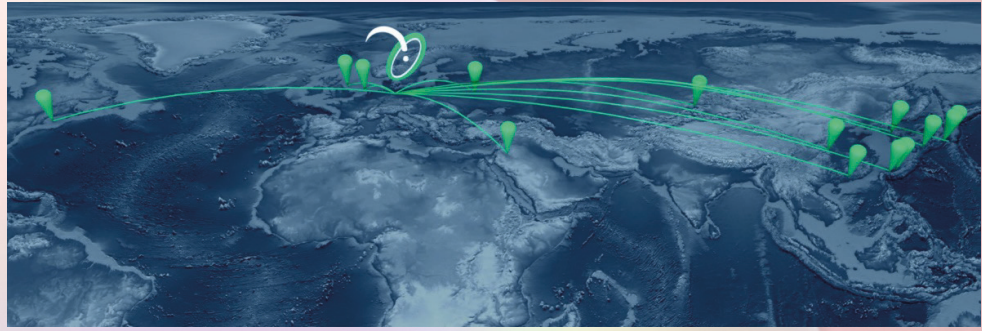


¹ LOR, Lift-off resist from Kayaku Advanced Materials, US, available from MRT,

² UL1 organic underlayer available from MRT

Nanoimprint Lithography

Distribution partners



China

Shaanxi Siddhi Info-Resource Co., Ltd. (Shanghai)
Web: <http://www.cssid.com.cn>

Raymond & Co. (Hong Kong)
Web: http://www.raymondnco.com/en_hk/rnct

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All Radiance Optronics Co., Ltd. (Taoyuan City)
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AHEAD Optoelectronics, Inc. (Taoyuan City)
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